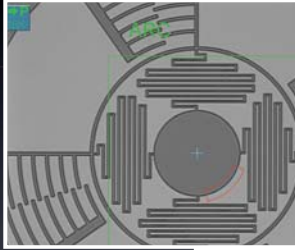
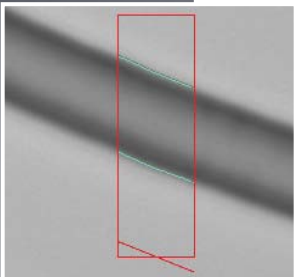


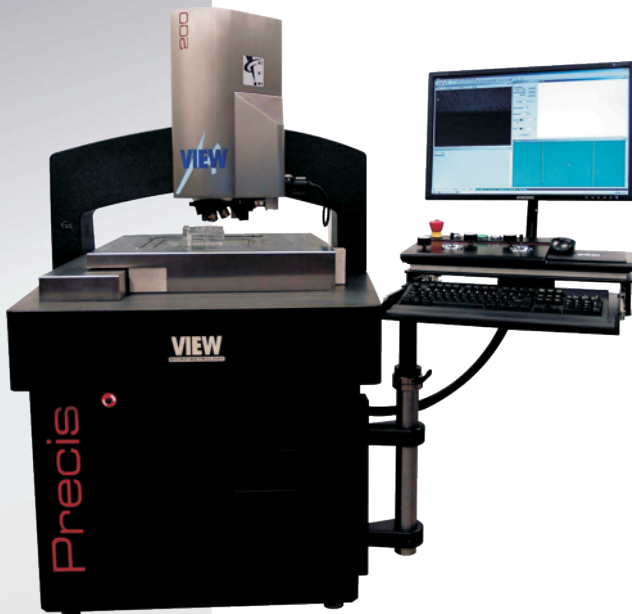
Precis 200



Measure linewidth, arc, circle diameters, and other features on micro-electronic devices.



Measure pitch, width, and spacing of flexures on MEMS devices.



**Global.
Agile.
Expert.**

Photo Description: VIEW Micro-Metrology Precis 200 with extended Z. Optical critical-dimension metrology system. Additional options are listed in the technical specifications and are not included in this photo.

The **Precis[®] 200** is an optical critical-dimension metrology system for micro-components, wafers, masks, MEMs, and HDD heads. The Precis combines precision stages, proven microscope optics, and a choice of three world-class metrology software packages to provide new levels of capability for process metrology. The Precis delivers sub-micron field-of-view and point-to-point measurement accuracy on wafers, masks, and micro-fabricated parts.

- **Micro-Measure™ 200 x 200 mm Precision Needle Bearing X-Y Stage**
- **Dual Loop Servo Motion Control for Precise and Stable Part Translation**
- **Exclusive Micro Focus Block™ Focus Assembly Provides Rigid, Repeatable Focus Motion**
- **6-Position Turret Allowing an Objective Magnification Range from 5-150x**
- **Ergonomic Control Station and Compact Footprint**

Typical applications for the Precis include:

- **Sub-Micron Measurement**
 - Micro-components
 - Electronic packages
 - Blades
 - Suspensions
 - Probe cards
 - Lead-frames
 - Micro-BGAs
- **Critical Dimension and Registration Measurements**
 - Linewidth
 - Overlay
 - MEMs devices
 - Contacts
 - Ink-jet print heads
 - HDD Heads
 - Tape heads

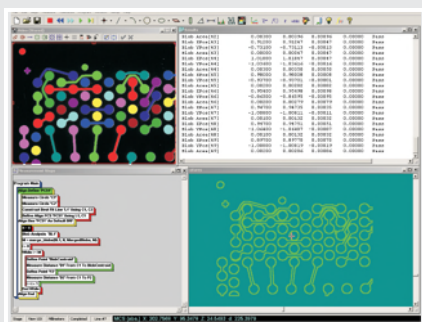


Precis 200

VIEW Metrology Software (VMS) is designed for the most demanding video CMM applications.

VMS provides extensive capabilities to easily handle difficult lighting conditions, weak edges, and part-to-part variability. Advanced features, such as Step and Repeat, Local Alignments, CAD Import, and Part Family Programming make complex part layouts easy to set up. VMS also provides a host of customizable features, such as programming variables, branching and looping, and "If-Then-Else" type statements to make the inspection process adaptable to your process control needs.

- Multifunction tools (Blob and Centroid) allow for flaw detection and feature presence/absence checking
- Unique tree-view program editor
- CAD import and offline programming to reduce program set-up time
- Optional parameter adjustments to fine-tune measurement recipes
- Optional MMWin/CD & Overlay metrology software is available for wafer or mask measurements



VMS — VIEW Metrology Software

HOURS

HOURS Industrial Equipment(HK) Co.,Ltd

HK FAX: (852)39809387 FAX: (852)39809397
 DG FAX: 0769-87056205 FAX: 0769-89026335

MAIL: info@hours-web.com

URL: www.hours-web.com

Technical Specifications

Standard Optional

Measurement Range 200 x 200 x 5 mm 200 x 200 x 75 mm
Stage Type Proprietary Micro-Measure™ hand-crafted, needle bearing stage design
Stage Drive System All DC servo motor; X,Y,Z Extended Z axis; linear motor drive
X-Y-Z Positional Resolution 0.01 μm

Optics* — Typical Set-Up

Objective Lens	5x	10x	20x	50x	100x	
Pixel Size	0.00298	0.00142	0.00072	0.000296	0.000143	
Working Distance (mm)	23.5	17.5	4.5	1	1	
Field of View (mm)	X	1.90	0.950	0.48	0.190	0.095
	Y	1.30	0.65	0.35	0.14	0.070

*Other optical configurations available

Camera Monochrome Digital 1.4 Mega Pixel
 Monochrome Digital 2.0 Mega Pixel
 Color digital 2.0 Mega Pixel

Illumination Programmable tungsten halogen coaxial reheated light
 Programmable LED transmitted light with auto N.A stop

Facilities Requirements Power: 110V, 1Φ, 60 Hz or 220V, 1Φ, 50 Hz
 Temperature: 18-20° +/- 0.1°C
 Vibration: ISO VCB class (≤1000 μ-inch/sec; 68 db max)
 House vacuum: 10-inches Hg (35 kPa) — for optional vacuum wafer chuck

FOV Measurement Accuracy ≤ 0.01 μm (100x)

FOV Measurement Repeatability ≤ 0.01 μm (on wafers or photomasks with 100x objective lens)

Measurement Accuracy $E_z(XY \text{ plane}) = 0.25 + 2L/1000$

MTBF ≥ 4,000 hours

ESD Control Options Class 1000 clean room compatible Class 100 clean room compatible

System Dimensions (W x D x H) 1600 x 1250 x 1700 mm

Weight Crated: 1100kg Uncrated: 950kg

Features and Accessories

Software VMS (VIEW Metrology Software)
 Elements™ self-programming SMT metrology software
 MMWin — CD & Overlay metrology software

Controller Intel® Core™ 2 Duo E6320 processor and Windows® XP operating system with 20" flat panel monitor, joystick, keyboard, and mouse

Workstation Integrated operator workstation: an adjustable, mounted platform that provides support for the flat panel display, control panel, and peripherals

Imaging Sensors Thin Film Thickness (TFT)

Precis 200 Footprint Dimensions (mm)

